IN THE CLAIMS

1 (Previously Presented). A method comprising:

forming a pore in an insulator;

forming a heater in said pore by filling said pore with a conductive material and then removing the upper portion of said conductive material;

filling the upper portion with a phase change material that extends over said insulator;

forming a substantially planar upper surface of said phase change material; and

forming a substantially planar upper electrode over said substantially planar upper surface of said phase change material.

Claims 2 and 3 (Canceled).

4 (Previously Presented). The method of claim 1 including planarizing the upper surface of said insulator.

Claims 5 and 6 (Canceled).

7 (Previously Presented). The method of claim 1 including patterning and etching said phase change material over said insulator.

8 (Original). The method of claim 7 including forming a T-shaped phase change material.

9 (Original). The method of claim 3 including forming a sidewall spacer in said pore.

10 (Original). The method of claim 9 including depositing metal in said pore after forming said sidewall spacer.

Claims 11-31 (Canceled).